



Memory Devices Based on Two-Dimensional Materials

Guest Editors:

Dr. Shupeng Chen

School of Microelectronics,
Xidian University, Xi'an 710126,
China

Dr. Wei Li

School of Microelectronics,
Northwestern Polytechnical
University, Xi'an 710072, China

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Message from the Guest Editors

We are pleased to invite you to publish your research in this Special Issue on “Memory Devices Based on Two-dimensional Materials” in *Micromachines*. Memory devices are essential components of electronic systems, and their performance and power efficiency play important roles in determining the overall system performance. The emergence of two-dimensional (2D) materials has opened new possibilities for developing memory devices that offer higher performance and lower power consumption. This Special Issue aims to solicit relevant work in memory devices based on various 2D materials, including graphene, transition metal dichalcogenides (TMDs), black phosphorus, 2D organic materials, etc. The research directions include but are not limited to the preparation of new materials, improvement of device structures, applications of storage devices, simulations of device and materials, etc. In this Special Issue, original research articles and reviews are welcome.





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Editor-in-Chief

Message from the Editor-in-Chief

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Micromachines Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland

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